

Jan Doise

List of Publications by Year in descending order

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Version: 2024-02-01

19
papers

161
citations

1684188

5
h-index

1199594

12
g-index

19
all docs

19
docs citations

19
times ranked

236
citing authors

#	ARTICLE	IF	CITATIONS
1	Influence of Homopolymer Addition in Templated Assembly of Cylindrical Block Copolymers. ACS Nano, 2019, 13, 4073-4082.	14.6	3
2	Strategies for Increasing the Rate of Defect Annihilation in the Directed Self-Assembly of High- χ Block Copolymers. ACS Applied Materials & Interfaces, 2019, 11, 48419-48427.	8.0	11
3	Defect mitigation in sub-20nm patterning with high- χ , silicon-containing block copolymers. , 2019, , .		2
4	Impact of annealing temperature on DSA process: toward faster assembly kinetics (Conference) Tj ETQq0 0 0 rgBT /Overlock 10 Tf 50 62		2
5	Studying the effects of chemistry and geometry on DSA hole-shrink process in three dimensions. , 2018, , .		1
6	Via patterning in the 7-nm node using immersion lithography and graphoepitaxy directed self-assembly. Journal of Micro/ Nanolithography, MEMS, and MOEMS, 2017, 16, 023506.	0.9	5
7	Dual brush process for selective surface modification in graphoepitaxy directed self-assembly. , 2017, , .		4
8	High- χ , Si-Containing Block Copolymers and Process Strategies for Directing Their Self-Assembly. Journal of Photopolymer Science and Technology = [Fotoporima Konwakai Shi], 2017, 30, 187-190.	0.3	2
9	Dual brush process for selective surface modification in graphoepitaxy directed self-assembly. Journal of Micro/ Nanolithography, MEMS, and MOEMS, 2017, 16, 1.	0.9	2
10	EUV patterned templates with grapho-epitaxy DSA at the N5/N7 logic nodes. Proceedings of SPIE, 2016, , .	0.8	5
11	Influence of template fill in graphoepitaxy DSA. , 2016, , .		2
12	Sub-5 nm Patterning by Directed Self-Assembly of Oligo(Dimethylsiloxane) Liquid Crystal Thin Films. Advanced Materials, 2016, 28, 10068-10072.	21.0	64
13	Influence of template fill in graphoepitaxy directed self-assembly. Journal of Micro/ Nanolithography, MEMS, and MOEMS, 2016, 15, 031603.	0.9	9
14	Integration of a templated directed self-assembly-based hole shrink in a short loop via chain. Journal of Micro/ Nanolithography, MEMS, and MOEMS, 2016, 15, 043505.	0.9	3
15	Implementation of surface energy modification in graphoepitaxy directed self-assembly for hole multiplication. Journal of Vacuum Science and Technology B: Nanotechnology and Microelectronics, 2015, 33, 06F301.	1.2	13
16	DSA graphoepitaxy calibrations for contact hole multiplication. Proceedings of SPIE, 2015, , .	0.8	3
17	Implementation of templated DSA for via layer patterning at the 7nm node. , 2015, , .		17
18	Contact hole multiplication using grapho-epitaxy directed self-assembly: process choices, template optimization, and placement accuracy. Proceedings of SPIE, 2014, , .	0.8	7

#	ARTICLE	IF	CITATIONS
19	Process optimization of templated DSA flows. , 2014, , .		6